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Masked Projection Stereolithography:

Improvement of the Limaye Model for Curing Single Layer Medium Sized Parts

A THESIS PRESENTED IN PARTIAL FULFILLMENT OF THE

REQUIREMENTS FOR THE DEGREE OF

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PREFACE

The author declares that this is his own work except where due acknowledgement has been given. It is being submitted for the PhD in Engineering, majoring in Mechatronics to the Massey University, Albany, New Zealand.

This thesis describes the research carried out by the author at the School of Engineering and Advanced Technology, Massey University, Albany, New Zealand from February 2004 to March 2008, supervised by Dr. J. Potgieter.

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